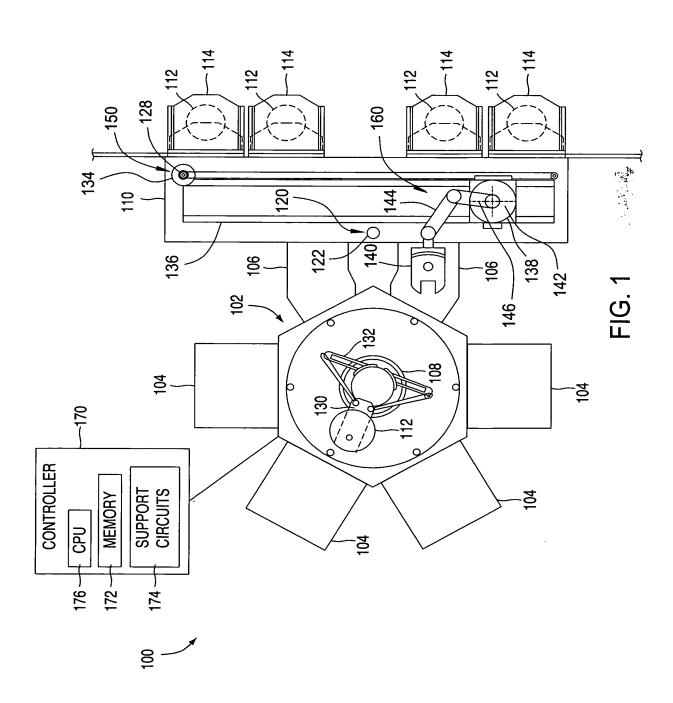
Sheet 1 of 6
Applicant: Yim, et al.
Title: METHOD AND APPARATUS FOR
MONITORING THE POSITION OF A
SEMICONDUCTOR PROCESSING ROBOT
Docket: 7954/DSM/BCVD/JW

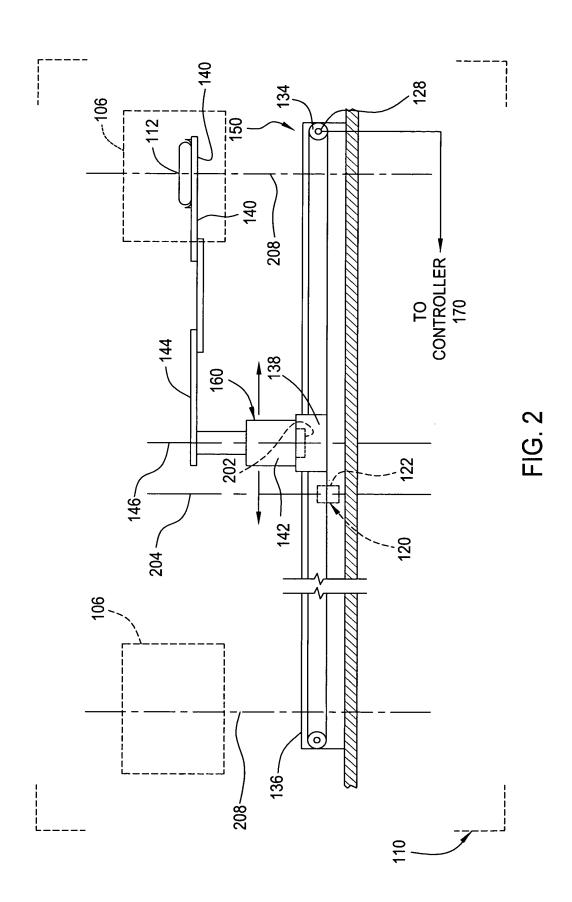
1/6



 $ldsymbol{f L}$

Sheet 2 of 6
Applicant: Yim, et al.
Title: METHOD AND APPARATUS FOR
MONITORING THE POSITION OF A
SEMICONDUCTOR PROCESSING ROBOT
Docket: 7954/DSM/BCVD/JW





Sheet 3 of 6
Applicant: Yim, et al.
Title: METHOD AND APPARATUS FOR
MONITORING THE POSITION OF A
SEMICONDUCTOR PROCESSING ROBOT
Docket: 7954/DSM/BCVD/JW

Γ

3/6

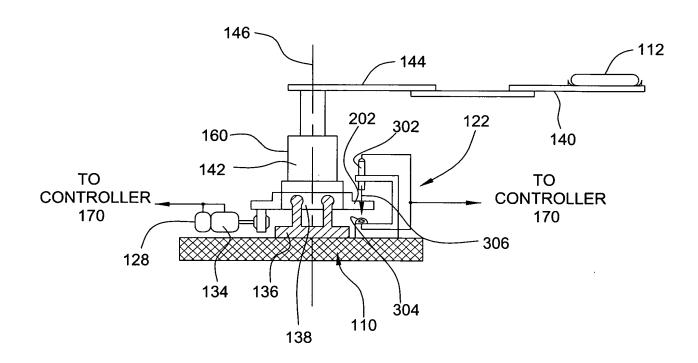
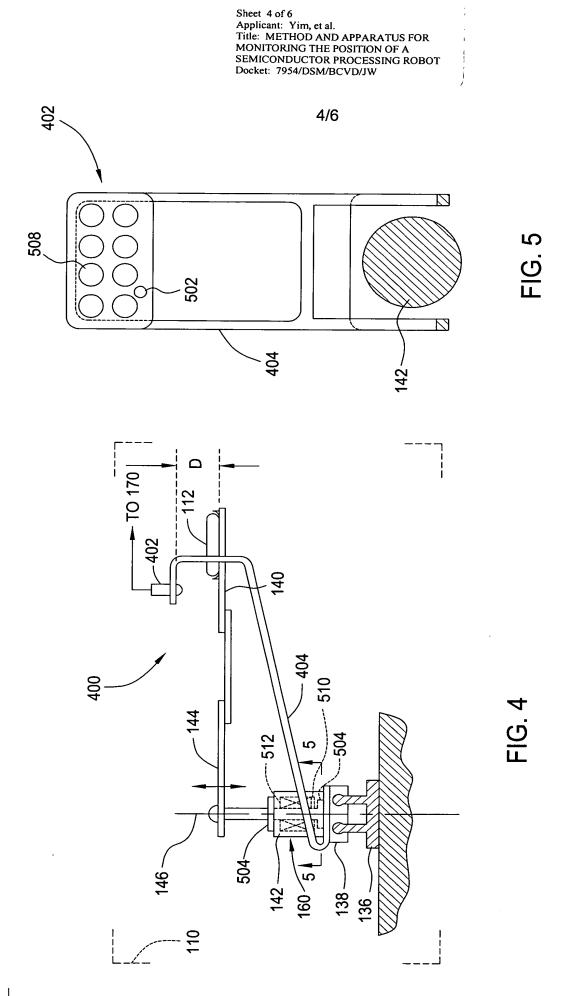


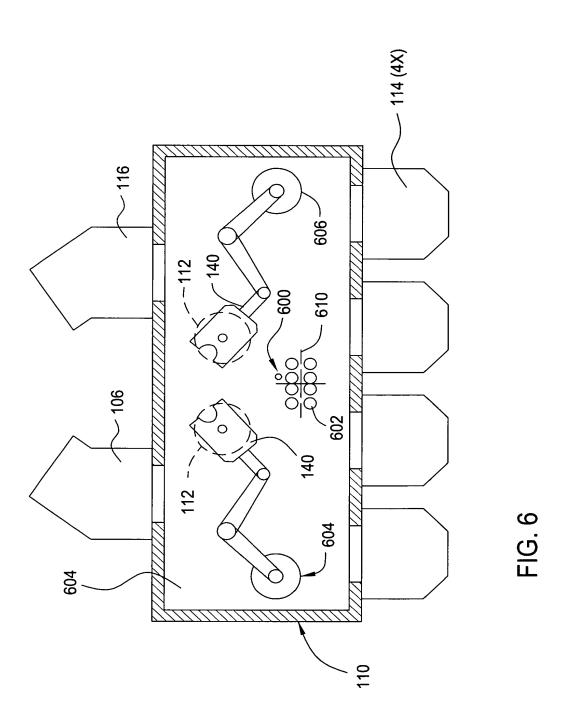
FIG. 3



Sheet 5 of 6
Applicant: Yim, et al.
Title: METHOD AND APPARATUS FOR
MONITORING THE POSITION OF A
SEMICONDUCTOR PROCESSING ROBOT
Docket: 7954/DSM/BCVD/JW

 \neg

5/6



Sheet 6 of 6
Applicant: Yim, et al.
Title: METHOD AND APPARATUS FOR
MONITORING THE POSITION OF A
SEMICONDUCTOR PROCESSING ROBOT
Docket: 7954/DSM/BCVD/JW

6/6

